



03500.015382

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: Mr. Brian L. Mutschler
TAKAHARU KONDO ET AL.	)	
	:	Art Unit: 1753
Application No.: 09/866,665	)	
	:	
Filed: May 30, 2001	)	
	:	
For: SILICON-TYPE THIN FILM	)	
FORMATION PROCESS, SILICON	:	
TYPE THIN FILM, AND	)	
PHOTOVOLTAIC DEVICE	:	May 7, 2004

Commissioner for Patents  
 Mail Stop: AF  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

In response to the Office Action dated February 9, 2004, please amend the above-identified application as follows prior to the further examination thereof pursuant to the accompanying Request for Continued Examination.